## **Electronic Supplementary Information (ESI):**

# Investigation of modified Nanopore Arrays by FIB/SEM Tomography

Angelika Holzinger<sup>a</sup>, Gregor Neusser<sup>a</sup>, Benjamin J. J. Austen<sup>b</sup>, Alonso Gamero-Quijano<sup>c</sup>, Gregoire Herzog<sup>c</sup>, Damien W. M. Arrigan<sup>b</sup>, Andreas Ziegler<sup>d</sup>, Paul Walther<sup>d</sup>, Christine Kranz<sup>a,†</sup>

Catalan instituct for Failed and Microbiologie pour les Matériaux et l'Environment (LCPME), UMR 7564, CNRS-Université de Lorraine, 405 rue de Vandoeuvre, 54600 Villers-les-Nancy, France.

+ presenting author.



**Fig. S1:** Electrogeneration of the silica at the ITIES supported by a nanopore array. Chemical reactions of the silica formation at the ITIES (A), a schematic representation of the experimental set-up used for the silica electrodeposition (B) and a typical chronoamperogram recorded for the modification of a nanoporous array (C).

organic phase

10

0

20

30

deposition time [s]

40

50

60

<sup>&</sup>lt;sup>a.</sup> Institute of Analytical and Bioanalytical Chemistry, Ulm University, Albert-Einstein-Allee 11, 89081 Ulm, Germany.

<sup>&</sup>lt;sup>b</sup>. Curtin Institute for Functional Molecules and Interfaces & Department of Chemistry, Curtin University, Perth, Western Australia 6845, Australia.

<sup>&</sup>lt;sup>d.</sup> Zentrale Einrichtung Elektronenmikroskopie, Ulm University, Albert-Einstein-Allee 11, 89081 Ulm, Germany.

# Electronic Supplementary Information (ESI):



Fig. S2: Fabrication of a TEM foil as described in detail elsewhere<sup>1</sup>

- 1. SE imgae of the released sample area of the SiN membrane (TEM lamella) attached by beam induced deposition of Pt/C to the micromanipulator needle.
- 2. Removing the lamella (marked area) from the sample and bringing the lamella in close proximity to the Cu grid. The FIB image shows also the GIS needle for Pt/C deposition.
- 3. SE image of the mounting of the lamella by Pt/C deposition to the Cu grid.
- 4. Removing the micromanipulator needle by FIB-milling.
- 5. In a last step, the TEM lamella is thinned by FIB-milling to a thickness of 150 200 nm.



**Fig. S3:** SEM of a TEM lamella located at a TEM Cu grid (A), and SEM of the sample section characterized by EDX mapping (B). Signals according to the elemental composition are depicted in (C). Acceleration voltage: 10 kV.

# Electronic Supplementary Information (ESI):

### Mov. 1

STEM tomography of a nanopore array prior to electrochemical experiments. The membrane was tilted from -60° to 58.5° with 1.5° increment using an FEI Titan field emission microscope (FEI, ThermoFisher Scientific) at 300 kV acceleration voltage in parallel STEM mode, recording in the high angle annular dark field (HAADF) mode.

### Mov. 2

The movie represents the 3D FIB/SEM stack of the residue structure located towards the organic electrolyte facing side of the membrane shown in Fig. 5 in the manuscript. FIB slicing was performed at 30 kV and 48 pA; SEM images were recorded at 5 kV and 86 pA using the TLD detector. Tilt correction was applied. 80 slices with a frequency of 10 nm/slice were recorded.

### Mov. 3

3D FIB/SEM stack of the residue structure located towards the organic facing side of the membrane, according to Fig. 7 in the manuscript. . FIB slicing was performed at 30 kV and 48 pA; SEM images were recorded at 5 kV and 86 pA using the TLD detector. Cross-sections are recorded after tilt correction (38°). 300 slices with a frequency of 5 nm/slice were recorded and 116 slices are depicted.

### References

1 M. H. F. Overwijk, F. C. van den Heuvel and C. W. T. Bulle-Lieuwma, *J. Vac. Sci. Technol. B Microelectron. Nanom. Struct.*, 1993, **11**, 2021–2024.